

6007 - Std-MEMS / NEMS

6007 - Std-MEMS / NEMS New Standard: Guide for Use of Test Patterns for Characterizing a Deep Reactive Ion Etching (DRIE) Process

Reject

AFF_SEC

490364 - FUKUNAGA, Tsukasa

- Wrong document number is on the header, '6007', instead 6607.
- In 5.2.9, the order of the etch rate definition seems reversed. It should be 'the etch depth divided by the process time'.

AcceptComments

AFF_ITSdI

290498 - Vargas-Bernal, Rafael

- Reference in 11.1 is incomplete.

Total Voting Interests/Votes: 89/94**Voting Interest Accepts: 36 (97.30%)****Voting Interest Rejects: 1****Voting Interest Returns: 41****Return Percentage: 63.08%****Voting Interest Distribution: 65**